

BRS: 32 with 33

 Pending Active

- L1: (1) 10/612914
- L2: (43512) solid adj solution
- L3: (137593) ferr?electric ferr? adj electric ferr?magnetic ferr? adj magnetic FeRar
- L4: (1363423) electrode contact adj layer
- L5: (5276813) lower bottom
- L6: (4513372) upper top
- L7: (45744) 5 adj 4
- L8: (47) 2 with 7
- L10: (4) ("6541375" "6440754") pn.
- L9: (1) 18.693
- L11: (1071031) dop\$4 impurit\$3 ion near3 implant\$3 diffus\$4
- L12: (87551) 11 near5 metal\$4
- L13: (14) 8 and 12
- L14: (4) 9 and 12
- L15: (4431505) solution
- L16: (1896) 7 near8 15
- L17: (289562) dop\$4
- L18: (3537035) metal\$4
- L19: (7788) 15 near4 17
- L20: (436) 10 near4 18
- L21: (1) 18 same 20
- L22: (2) 16 and 20

 Failed

	Invator	Document	Issue#	Title	Current	Current	XRef	Review	S	C	R	W	3	Image	Doc#	P
1	<input checked="" type="checkbox"/>	Katori, Kenji	US 6479849	20021.1 Dielectric capacitor and memory and method	257/296	257/306			<input checked="" type="checkbox"/>	US 6479849						
2	<input checked="" type="checkbox"/>	Yeom, Seung	US 2004001	20040-1 Ferroelectric random access memory device	365/200				<input checked="" type="checkbox"/>	US 2004001						
3	<input checked="" type="checkbox"/>	Suzuki, Yukin	US 2003011	20030-1 Sputter target, barrier film and electronic co	257/751	257/767			<input checked="" type="checkbox"/>	US 2003011						
4	<input checked="" type="checkbox"/>	Yoshima, Yuk	US 2003007	20030-5 Tunable thin film capacitor	257/310	257/E21.00			<input checked="" type="checkbox"/>	US 2003007						
5	<input checked="" type="checkbox"/>	Natori, Eiji et	US 2003002	20030-7 Ceramic and method of manufacturing the sa	257/703	257/E21.27			<input checked="" type="checkbox"/>	US 2003002						
6	<input checked="" type="checkbox"/>	Takeuchi, Yu	US 2002001	20020-3 Piezoelectric/electrostrictive device and fabr	29/25.3				<input checked="" type="checkbox"/>	US 2002001						
7	<input checked="" type="checkbox"/>	Takeuchi, Yu	US 2002001	20020-4 Piezoelectric/electrostrictive device and pro	29/25.3	310/321			<input checked="" type="checkbox"/>	US 2002001						
8	<input checked="" type="checkbox"/>	Kawai, Kenji	US 2001005	20011.1 Semiconductor device, and method of manuf	257/301	257/309			<input checked="" type="checkbox"/>	US 2001005						
9	<input checked="" type="checkbox"/>	Takeuchi, Yu	US 6715192	20040-3 Method for manufacturing a piezoelectric/e	29/25.3	29/694			<input checked="" type="checkbox"/>	US 6715192						
10	<input checked="" type="checkbox"/>	Kawai, Kenji	US 6635561	20031.1 Semiconductor device, and method of manuf	438/622	257/E21.01			<input checked="" type="checkbox"/>	US 6635561						

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May 2004

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